

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18
Stylesheet Version v18.0

Title of
Invention

HIGH PRESSURE PROCESSING CHAMBER FOR
SEMICONDUCTOR SUBSTRATE

Application Number: 09/912844
Confirmation Number: 5915
First Named Applicant: Thomas Haverstock
Attorney Docket Number:
Search string: (6521466 or 6541278 or 6546946 or 6550484
or 6558475 or 6561213 or 6561220 or 6561481
or 6561767 or 6564826 or 5217043 or
20020001929).pn.



US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

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US Published Applications

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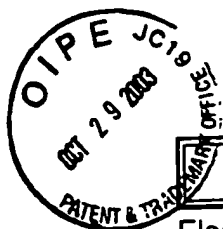
Remarks

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Non US Patent and Publication references shall be filed under a separate paper transmittal. The current electronic filing contains part 4 out of a total of 4 electronic filings. Fee has been paid in previous electronic filing.

Signature

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<p>Application Number: 09/912844</p> <p>Confirmation Number: 5915</p> <p>First Named Applicant: Maximilian Biberger</p> <p>Attorney Docket Number:</p> <p>Search string: (5900107 or 5904737 or 5932100 or 5934991 or 5981399 or 5989342 or 6005226 or 6017820 or 6029371 or 6037277 or 6053348 or 6056008 or 6077053 or 6082150 or 6085935 or 6097015 or 6128830 or 6145519 or 6159295 or 6164297 or 6203582 or 6216364 or 6239038 or 6241825 or 6251250 or 6277753 or 6286231 or 6305677 or 6334266 or 6344174 or 6388317 or 6389677 or 6418956 or 6436824 or 6454945 or 6464790).pn.</p>							
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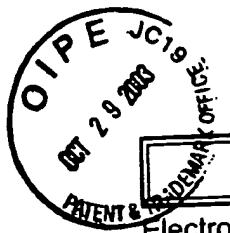
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Application Number: 09/912844
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First Named Applicant: Maximilian Biberger
Attorney Docket Number:
Search string: (5193560 or 5195878 or 5213485 or 5221019
or 5222876 or 5224504 or 5236669 or 5240390
or 5243821 or 5246500 or 5251776 or 5280693
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or 5746008).pn.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

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✓	17	5412958	1995-05-09	Iliff et al.
✓	18	5433334	1995-07-18	Reneau
✓	19	5447294	1995-09-05	Sakata et al.
✓	20	5503176	1996-04-02	Dunmire et al.
✓	21	5505219	1996-04-09	Lansberry et al.
✓	22	5509431	1996-04-23	Smith, Jr. et al.
✓	23	5571330	1996-11-05	Kyogoku
✓	24	5589224	1996-12-31	Tepman et al.
✓	25	5621982	1997-04-22	Yamashita et al.
✓	26	5629918	1997-05-13	Ho et al.
✓	27	5644855	1997-07-08	McDermott et al.
✓	28	5649809	1997-07-22	Stapelfeldt
✓	29	5656097	1997-08-12	Olesen et al.
✓	30	5669251	1997-09-23	Townsend et al.
✓	31	5702228	1997-12-30	Tamai et al.
✓	32	5706319	1998-01-06	Holtz
✓	33	5746008	1998-05-05	Yamashita et al.

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US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

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✓	5	4029517	1977-06-14	Rand			
✓	6	4091643	1978-05-30	Zucchini			
✓	7	4245154	1981-01-13	Uehara et al.			
✓	8	4341592	1982-07-27	Shortes et al.			
✓	9	4355937	1982-10-26	Mack et al.			
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✓	44	5186718	1993-02-16	Tepman et al.
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14	5288333	1994-02-22	Tanaka et al.
15	5339844	1994-05-23	Stanford Jr. et al.
16	5370741	1994-12-06	Bergman
17	5412958	1995-05-09	Bliff et al.
18	5433334	1995-07-18	Reneau
19	5447294	1995-09-05	Sakata et al.
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Remarks

Note: Remarks are not for responding to an office action.

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ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Worksheet Version v18.0

Title of Invention	HIGH PRESSURE PROCESSING CHAMBER FOR SEMICONDUCTOR SUBSTRATE						
Application Number:	09/912844	*09/912844*					
Confirmation Number:	5915						
First Named Applicant:	Maximilian Silberger						
Attorney Docket Number:							
Search string:	(2617719 or 2625886 or 3744660 or 3968885 or 4029517 or 4091643 or 4245154 or 4341592 or 4355937 or 4367140 or 4406596 or 4422651 or 4474199 or 4522788 or 4549467 or 4592306 or 4601181 or 4626509 or 4670126 or 4682937 or 4693777 or 4749440 or 4778356 or 4789077 or 4823976 or 4825808 or 4827867 or 4838476 or 4865061 or 4879431 or 4917556 or 4924892 or 4951601 or 4960140 or 4983223 or 5011542 or 5044871 or 5062770 or 5071485 or 5105556 or 5167716 or 5169296 or 5169408 or 5186718 or 5188515 or 5190373 or 5191993).pn.						
US Patent Documents							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
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<input checked="" type="checkbox"/>	3	3744660	1973-07-10	Gaines et al.			
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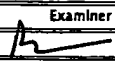
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Remarks

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OCT 31 2003

U.S. Department of Commerce
Patent and Trademark Office

Attorney Docket No.: SSI-00501

Serial No.: 09/912,844

INFORMATION DISCLOSURE STATEMENT BY APPLICANT
(Use Several Sheets if Necessary)

Applicants: Maximilian A. Biberger et al.

(37 CFR § 1.98(b))

Filing Date: July 24, 2001

Group Art Unit: 1763

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		Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation	
							Yes	No
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FORM PTO-1449
(Modified)U.S. Department of Commerce
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Attorney Docket No.: SSI-00501

Serial No.: 09/912,844

INFORMATION DISCLOSURE STATEMENT BY APPLICANT
(17 CFR § 1.98(b))

Applicants: Maximilian A. Biberger et al.

Filing Date: July 24, 2001

Group Art Unit: 1763

FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS

		Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation	
							Yes	No
	BJ							
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